

IN THE UNITED STATES PATENT AND TRADEMARK OFFICE

In re the Application of

Isao YOKOKAWA et al.

Application No.: New US Application

Filed: February 23, 2004

Docket No.: 118749

For: METHOD FOR PRODUCING SOI WAFER AND SOI WAFER

INFORMATION DISCLOSURE STATEMENT

Commissioner for Patents
P.O. Box 1450
Alexandria, VA 22313-1450

Sir:

Pursuant to 37 CFR §1.56, the attention of the Patent and Trademark Office is hereby directed to the reference(s) listed on the attached PTO-1449. Unless otherwise indicated herein, one copy of each reference is attached. It is respectfully requested that the information be expressly considered during the prosecution of this application, and that the reference(s) be made of record therein and appear among the "References Cited" on any patent to issue therefrom.

- ☒ 1. This Information Disclosure Statement is being filed (a) within three months of the U.S. filing date of this non-CPA application, OR (b) before the mailing date of a first Office Action on the merits in the present application. No certification or fee is required.
- ☒ 2. Relevance of the non-English language references is discussed in the present specification.
- ☒ 3. English-language Abstracts of the non-English language references Nos. 1-2 are attached hereto.
- ☒ 4. A computer-generated English translation of the following Japanese Patent Publication has been obtained from the website of the Japanese Patent Office ([<http://www.jpo.go.jp>]), and is attached, but has not been reviewed for accuracy. See References 1-2.

Respectfully submitted,



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DEPOSIT ACCOUNT USE AUTHORIZATION Please grant any extension necessary for entry; Charge any fee due to our Deposit Account No. 15-0461
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Form PTO-1449 (REV. 8-83)		US Dept. of Commerce PATENT & TRADEMARK OFFICE		ATTY DOCKET NO. 118749		APPLICATION NO. New US Application	
INFORMATION DISCLOSURE STATEMENT (Use several sheets if necessary)				APPLICANTS Isao YOKOKAWA et al. FILING DATE February 23, 2004			
U.S. PATENT DOCUMENTS							
EXAMINER INITIAL		DOCUMENT NUMBER	DATE	NAME	CLASS	SUB CLASS	
FOREIGN PATENT DOCUMENTS							
		DOCUMENT NUMBER	DATE	COUNTRY	CLASS	SUB CLASS	
	1	JP A 11-307472 (with abstract and translation)	11/05/1999	Japan			
	2	JP A 5-211128 (with abstract and translation)	08/20/1993	Japan			
OTHER DOCUMENTS (Including Author, Title, Date, Pertinent Pages, etc.)							
	3	Eltran et al, "Science in Silicon", Surface Science Technology Series, Realize Inc., pp 443-496					
EXAMINER				DATE CONSIDERED			
Examiner: Initial if citation considered, whether or not citation is in conformance with M.P.E.P. 609; draw line through citation if not in conformance and not considered. Include copy of this form with next communication to applicant.							

Date: February 23, 2004